

Features

- Double Poly / Double Metal
- 3 μm Poly and Metal I Pitch
- 5.5 Volts Maximum Operating Voltage
- 2.7~3.6 Volts Low Voltage Option
- 1.2 Volts Very Low Voltage Option
- Direct shrink of Mitel 2 μm design rules
- Low TCR Resistor Module
- ProToDuction[™] Option for fast prototypes
- Standard Cells Library

Description

The 1.5 μm process provides flexibility, speed and packing density needed in mixed signal designs. The aggressive design rules make it comparable to most 1.2 μm processes. A 3 volts and a 1.2 volts options are also available for low voltage applications, they offer low and matched threshold voltages for improved dynamic range. A process module can be integrated to provide high precision and very low TCR polysilicon resistors.

Technology Outline

- Drain Engineered Structure to Ensure Reliability against Hot-Carrier Injection
- Planarization with SOG Sandwich Structure
- Nitride Passivation for Reliability against Moisture
- Latchup Free Process on Non-Epi Material Achieved with Optimized I/O Protection (patent pending)

Process Parameters

Process Parameters	1.5 μm 5volts & 3volts	Units
Metal I pitch (width/space)	1.5 / 1.5	μm
Metal II pitch (width/space)	2.0 / 1.8	μm
Poly pitch (width/space)	1.5 / 1.5	μm
Contact	1.5 x 1.5	μm
Via	1.8 x 1.8	μm
Gate geometry	1.5	μm
P-well junction depth	3.0	μm
N+ junction depth	0.28	μm
P+ junction depth	0.28	μm
Gate oxide thickness	270	Å
Inter poly oxide thick.	480	Å

MOSFET Electrical Parameters

Electrical Parameters	1.5 MICRON - 5 volts						Units	Conditions
	N Channel			P Channel				
	min.	typ.	max.	min.	typ.	max.		
Vt (10x1.2 μm)	0.55	0.70	0.85	0.55	0.70	0.85	V	saturation
I _{ds} (10x1.2 μm)		262			108		$\mu\text{A}/\mu\text{m}$	V _{ds} =V _{gs} =5v
Gain β (10x10 μm)		700			200		$\mu\text{A}/\text{V}^2$	
Body Factor (50x50 μm)		0.50			0.82		$\sqrt{\text{V}}$	
Bvdss	10	13		10	13		V	I _{ds} =20nA
Subthreshold Slope		91			110		mV/dec.	V _{ds} =0.1v
Maximum Substrate Current (50x1.2 μm)		0.20			.0004		$\mu\text{A}/\mu\text{m}$	V _{ds} =5.5v V _{gs} =2.7v
Field Threshold	10	19		10	19		V	I _{ds} = 14 μA
L Effective		1.2			1.2		μm	L drawn = 1.5 μm

1.5 Micron CMOS Process Family

Capacitances (fF/ μm^2)

	1.5 μm 5 volts & 3 volts		
	min.	typ.	max.
Inter-poly	0.62	0.68	0.84
Gate oxide	1.2	1.3	1.4
N+ Junction	0.42		
P+ Junction	0.62		

Resistances ($\Omega/\text{sq.}$)

	1.5 μm 5 volts & 3 volts		
	min.	typ.	max.
Pwell	5700		
Pfield in Pwell	2800	3200	3600
N+	35	45	55
P+	80	100	120
Poly gate	15	20	25
Poly capacitor	75	100	125
Metal I	0.038		
Metal II	0.038		

Bipolar gain¹

	1.5 μm - 5 volts		
	min.	typ.	max.
NPN vertical	180		

¹Test condition : $V_{ce} = 5$ volts

FIG 1 : I-V Characteristics for a 10x1.5 μm N-MOSFET (1.5 μm 5 volts process)

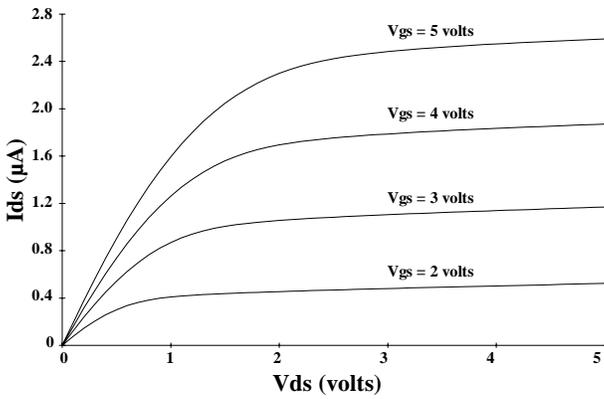


FIG 2 : I-V Characteristics for a 10x1.5 μm P-MOSFET (1.5 μm 5 volts process)

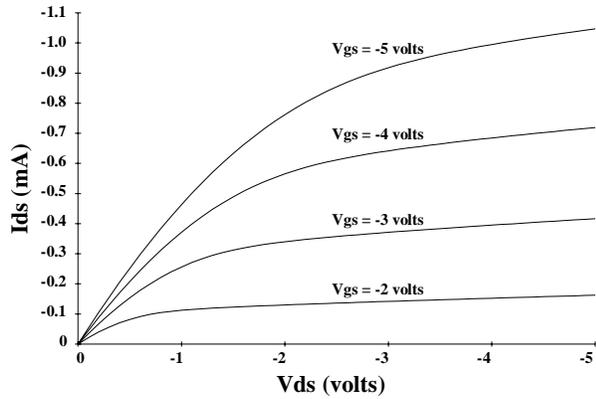


FIG 3 : Subthreshold Characteristics at $V_{ds}=0.1$ volt for a 10x1.5 μm N-MOSFET (1.5 μm 5 volts process)

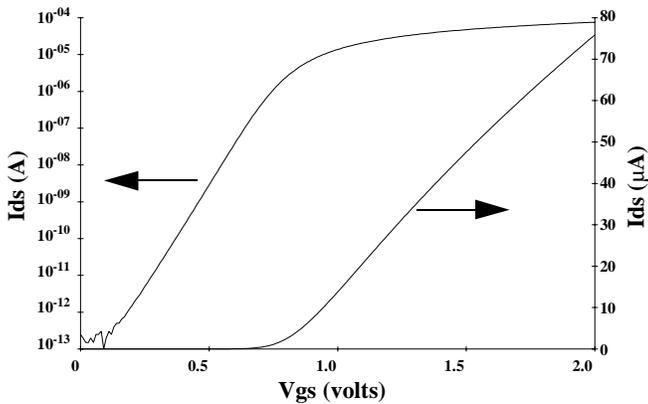
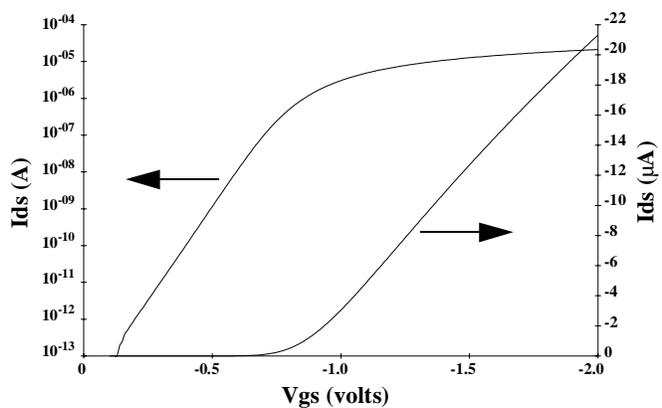


FIG 4 : Subthreshold Characteristics at $V_{ds}=-0.1$ volt for a 10x1.5 μm P-MOSFET (1.5 μm 5 volts process)



Note: These values are for guidance only. Many of them can be adjusted to suit customer requirements. For full process specifications contact a Mitel sales office or representative.